

Title (en)  
DEFORMATION MEASURING DEVICE

Title (de)  
VERFORMUNGSMESSER

Title (fr)  
DISPOSITIF DE MESURE DE DEFORMATION

Publication  
**EP 1127243 B1 20061102 (DE)**

Application  
**EP 99963212 A 19991104**

Priority  
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Abstract (en)  
[origin: WO0026608A2] The invention relates to a micromechanical sensor comprising electrodes (1, 2) which are arranged on a substrate, and comprising electrode bars (A) made of silicon that can move with regard to the electrodes. A deformation of the substrate is measured by determining the differential changes in capacity of these electrode bars in comparison to the adjacently arranged electrodes. Two groups of electrode bars are preferably used which are interlocked with one another in an alternating comb-like manner, which, separate from one another, are interconnected at the ends thereof in an electrically conductive manner, and which are anchored on the substrate.

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